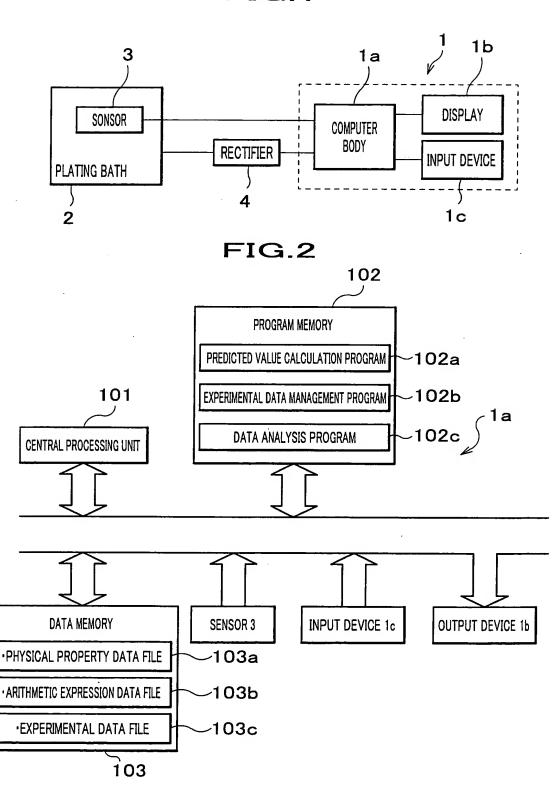
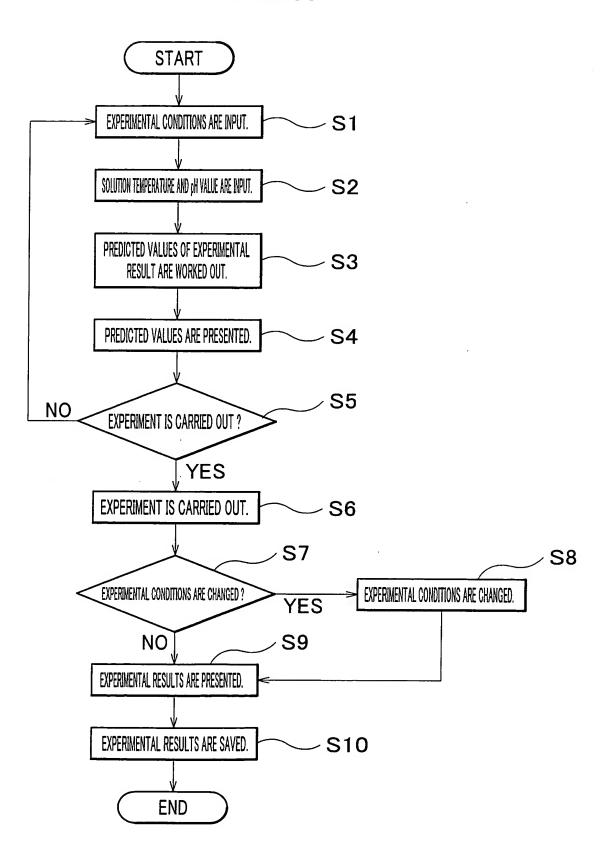


FIG.1

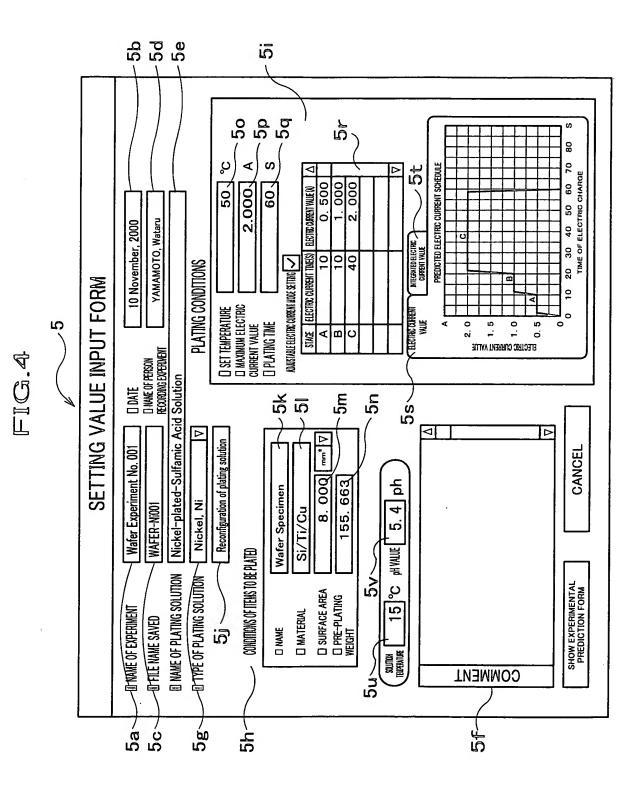


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FIG.3



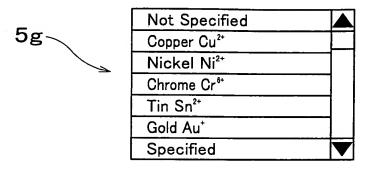
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FIG.5A



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FIG.5B

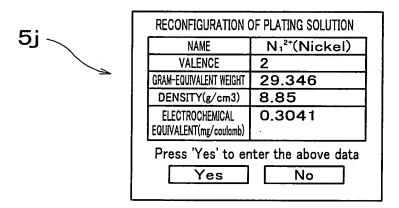
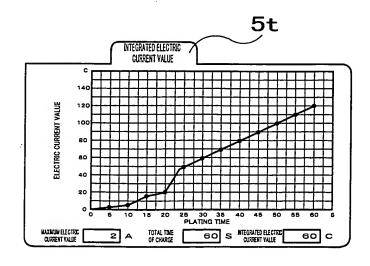
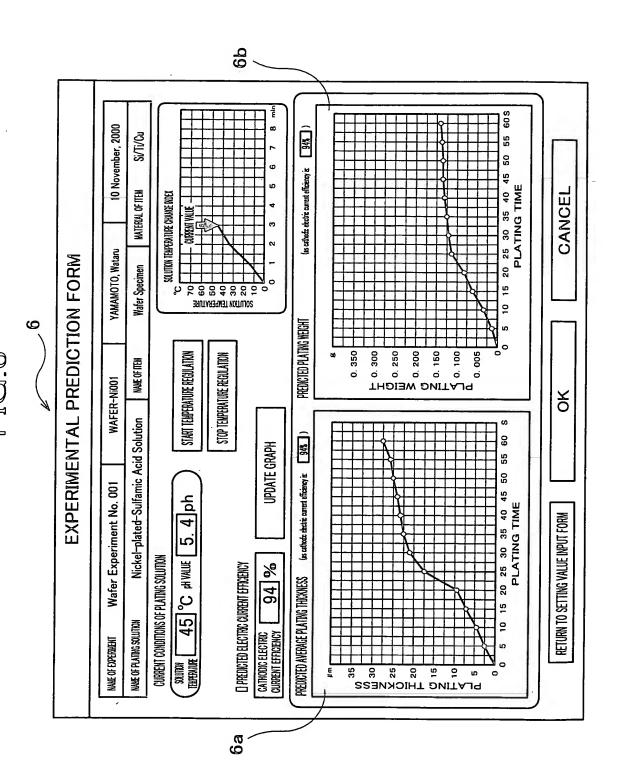


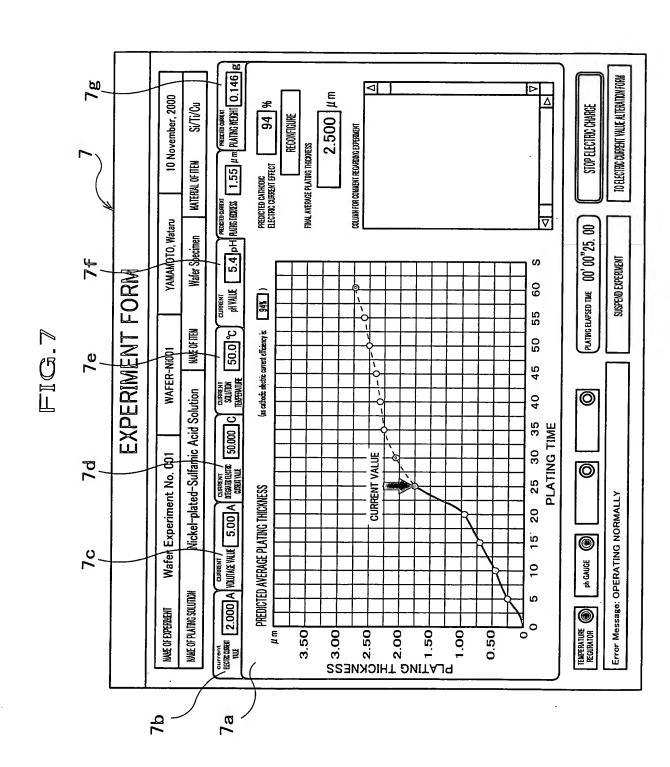
FIG.5C



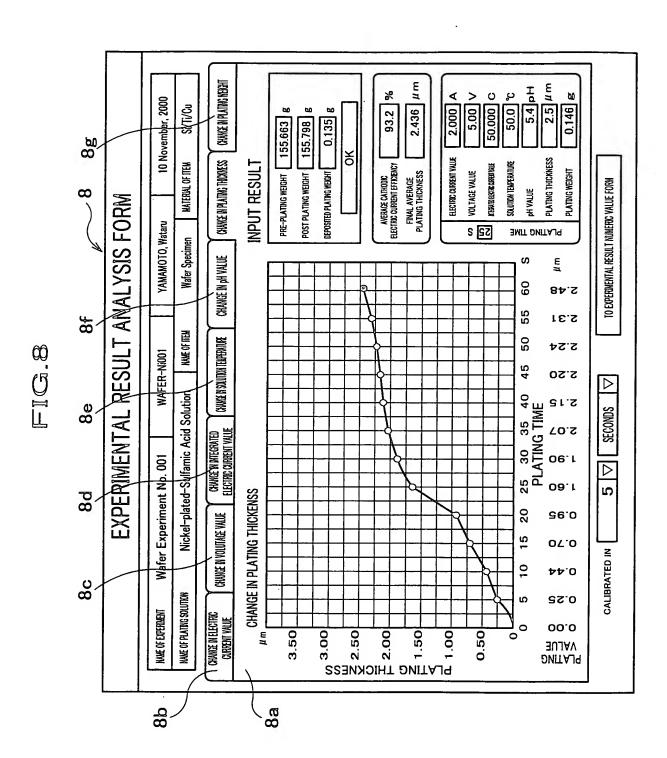
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	10 November, 2000	Si/Ti/Cu	PLATING WEICHTLE)	XXXX	XXXX	×××	XXXX	×××	X X X X	X X X X	X X X	XXXX	XXXX	XXXX	XXXX	XXX	XXXX																	
UE FORM		MATERIAL OF ITEM	PLATEG THOXOS SOLEM	XXXX	××××	XXXX	XXXX	X X X X	****	XXXX	XXXX	XXXX	×××	XXXX	XXXX	XXXX																		
CAL VAL	YAMAMOTO, Wataru	Wafer Specimen	AH VALUEGAD	XXXX	***	XXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX																					
EXPERIMENTAL RESULT NUMERICAL VALUE FORM	WAFER-Ni001	NAME OF ITEM	SOUTTON TEAPERATURE("C)	XXXX	××××	XXXX	××××	XXXX	× × ×	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX																	
L RESULI		c Acid Solution	NEGOTO ELENTE CHESTIVIEN	XXXX	××××	XXXX	7777	****	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX																		
A I MICIA I A	Wafer Experiment No. 001	Nickel-plated-Sulfamic Acid Solution	VOLTAGE VALLETA)	XXXX	XXXX	XXXX	XXXX	XXXX	××××	××××	××××	XXXX	××××	××××	XXXX	XXXX	××××	XXXX	XXXX	XXXX	××××	XXXX	XXXX	XXXX	****	***	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX
EXPE	Wafer Exp		ELECTRIC CURRENT VALUEIX	XXXX	XXXX	XXXX	XXXX	××××	×××	××××	XXXX	XXXX	XXXX	××××	××××	XXXX	XXXX	XXXX	××××	XXXX	××××	XXXX	***	XXXX	***	XXX	×××	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX	XXXX
	NAME OF EXPERIMENT	NAME OF PLATING SOLUTION	PLATING TIZE(S)	0	_	2	6	4	2	9	7	8	6	9	=	12	13	4	12	9	-	8	a c	20	30	23	24	. 52	26	27	28	29	30	31